

Description

The STAUFF Laser Particle Monitor System LPM 1 is a laser based 4-channel inline particle monitor designed for the continuous monitoring of particle contamination. The LPM 1 provides cumulative particle concentration information at $>4 \mu\text{m(c)}$, $>6 \mu\text{m(c)}$ and $>14 \mu\text{m(c)}$ sizes applicable to the ISO 4406, ISO 11943 and ISO 11171 requirements for optical particle counters. A $>21 \mu\text{m(c)}$ channel is also provided for larger particle concentration information. Machine operators are alerted to changes in particle contamination levels in a

machine's fluid by the indications provided from the LPM 1. The contamination level will be shown on the display or can be transmitted via the RS-232 serial port into a personal computer. With the ModBus-serial port the data can be transferred into a computer network or to an external display. The LPT particle transducer is configured via the IR-port on a Palm or Pocket Computer. The LPM 1 system consists of a Laser Particle Transducer LPT and a Laser Interface Module LIM (see functional diagram).



DIAGNOSTICS

Functional diagram

